Application Serial No. 10/075,172
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Filing Date February 13, 2002
Inventor B. E. Cron
Assignee Micron Technology, Inc.
Group Art Unit 37,23
Examiner Eziamara Anthony Ojini
Attorney's Docket No. Mi22-1804
Customer No. 021567
Title: Methods for Conditioning Surfaces of Polishing Pads After Chemical-Mechanical

RESPONSE TO NOVEMBER 19, 2003 OFFICE ACTION

To:

Commissioner for Patents

P.O. Box 1450

Polishing

Alexandria, VA 22313-1450

From:

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AMENDMENTS

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